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RECEIPT

Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

JOAN WANG

Serial No.: 09/882,141

Filed: June 15, 2001

For: METHOD OF ETCHING HIGH ASPECT
RATIO OPENINGS IN SILICON

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REQUEST FOR CORRECTED FILING RECEIPT

To: Assistant Commissioner for Patents
Washington, DC 20231

Sir:


The filing receipt for the above-identified application, a copy of which is attached, is incorrect in that there is only a single inventor, JOAN WANG, for parent application 08/867,229, rather than the three inventors listed on the filing receipt for this divisional application.

Please issue a corrected filing receipt.

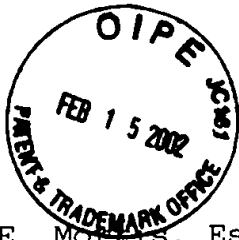
Respectfully submitted,

JOAN WANG

By


Birgit E. Morris

Reg. No. 24,484



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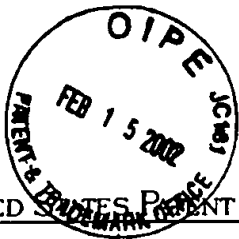
_____ Docket No. AM1562D1

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Please continue to send all correspondence to

Patent Counsel
Applied Materials, Inc
PO Box 450A
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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/882,141	06/15/2001	1733	710	AM1562D1	4	6	1

CONFIRMATION NO. 8856

FILING RECEIPT



OC000000006416924

Patent Counsel
Applied Materials, Inc
PO Box 450A
Santa Clara, CA 95052

RE

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Date Mailed: 08/13/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)Yiqiong Wang, Morgan Hill, CA;
~~Maocheng Li, Fremont, CA;~~
~~Shaohai Pan, San Jose, CA;~~**Domestic Priority data as claimed by applicant**

THIS APPLICATION IS A DIV OF 08/867,279 06/02/1997

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IC 1700**Foreign Applications**

If Required, Foreign Filing License Granted 08/10/2001

Projected Publication Date: 11/22/2001

Non-Publication Request: No

Early Publication Request: No

Title

Method of etching high aspect ratio openings in silicon

Preliminary Class

156

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Bib Data Sheet

CONFIRMATION NO. 8856

SERIAL NUMBER 09/882,141	FILING DATE 06/15/2001 RULE	CLASS 156	GROUP ART UNIT 1765	ATTORNEY DOCKET NO. AM1562D1	
APPLICANTS Yiqiong Wang, Morgan Hill, CA; ** CONTINUING DATA ***** THIS APPLICATION IS A DIV OF 08/867,229 06/02/1997 ** FOREIGN APPLICATIONS ***** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 08/10/2001					
Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowance Verified and Acknowledged _____ Examiner's Signature Initials		STATE OR COUNTRY CA	SHEETS DRAWING 4	TOTAL CLAIMS 6	INDEPENDENT CLAIMS 1
ADDRESS Patent Counsel Applied Materials, Inc PO Box 450A Santa Clara ,CA 95052					
TITLE Method of etching high aspect ratio openings in silicon					
FILING FEE RECEIVED 710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		